

1/3

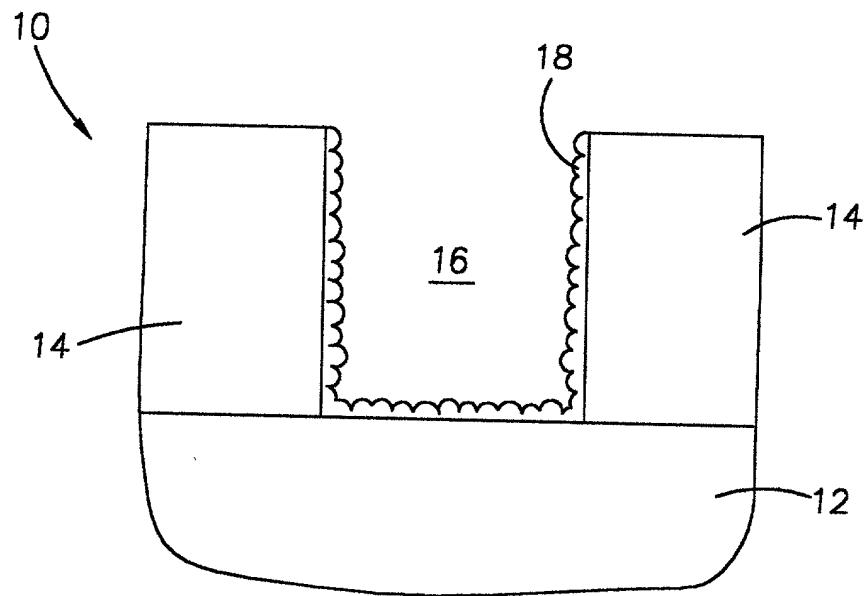


FIG.1

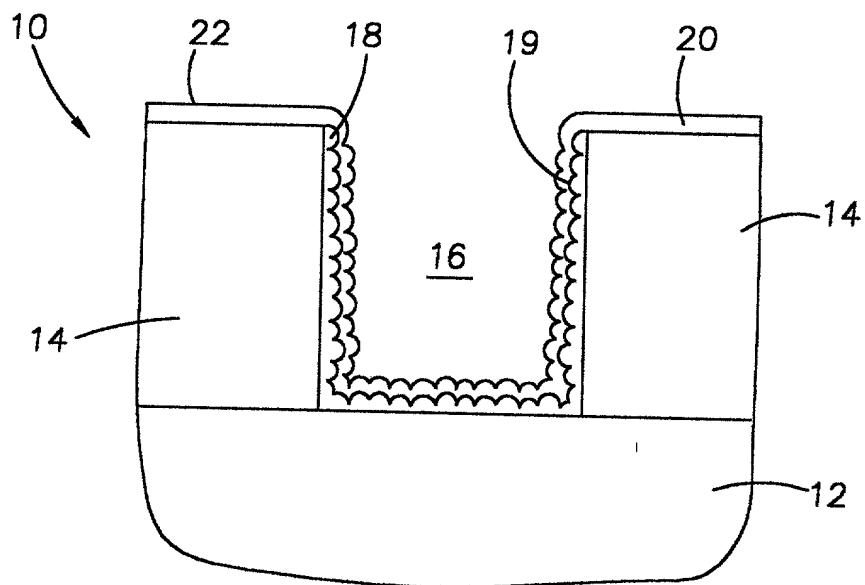


FIG.2

2/3

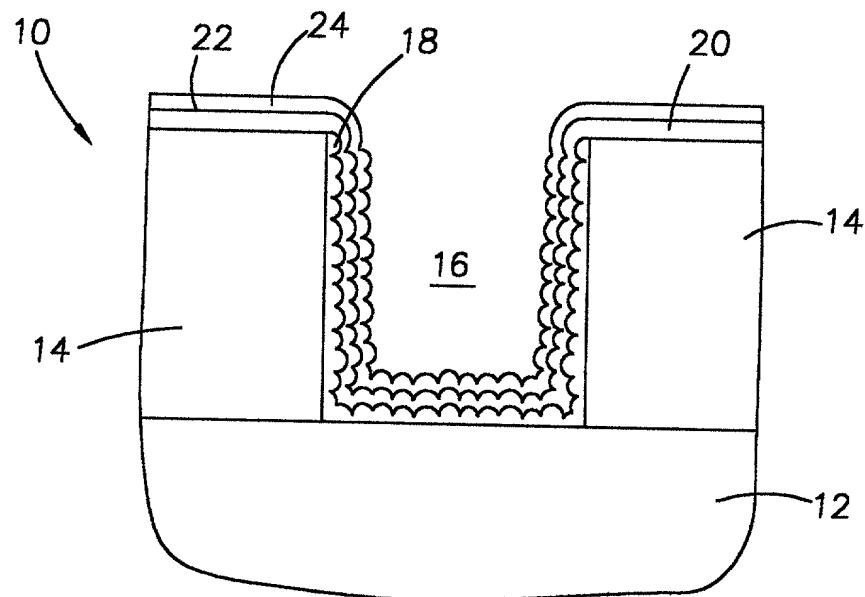


FIG.3

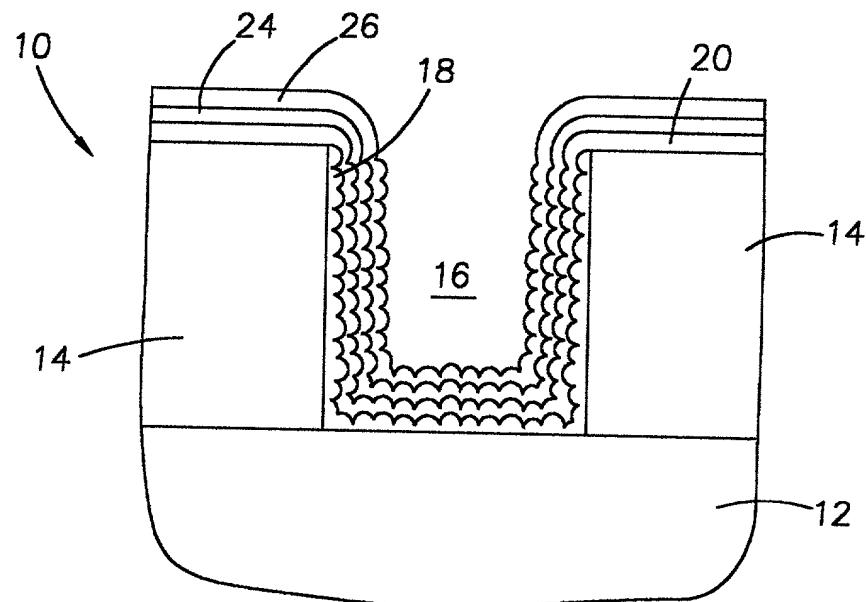


FIG.4

Applicant: Ronald A. Weimer  
For: Method of Improved High K  
Dielectric - Polysilicon Interface for  
CMOS Devices  
Atty Docket No. MTI-31532

3/3

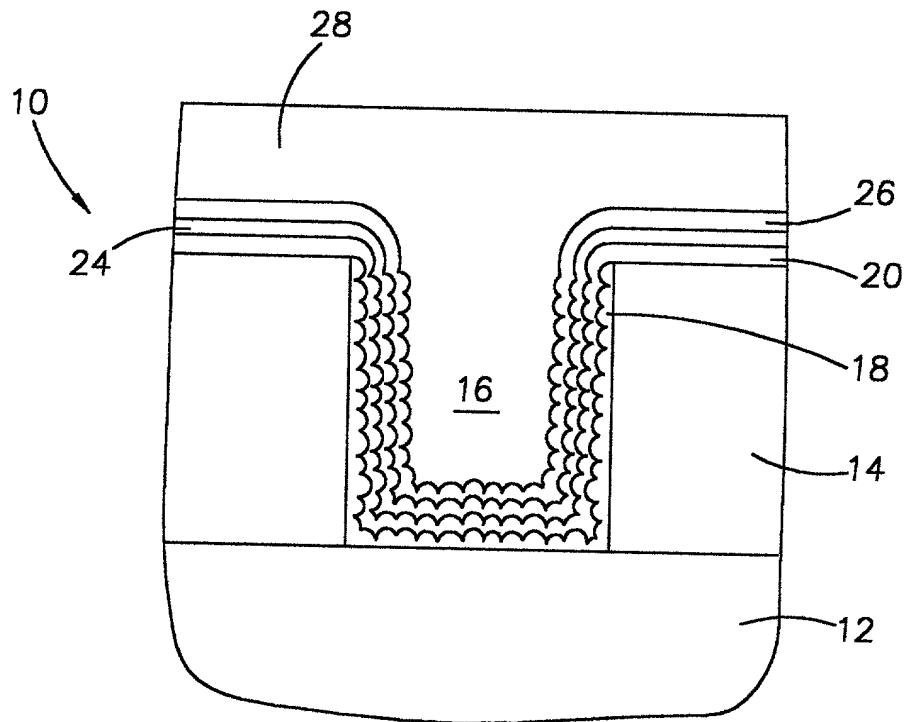


FIG. 5